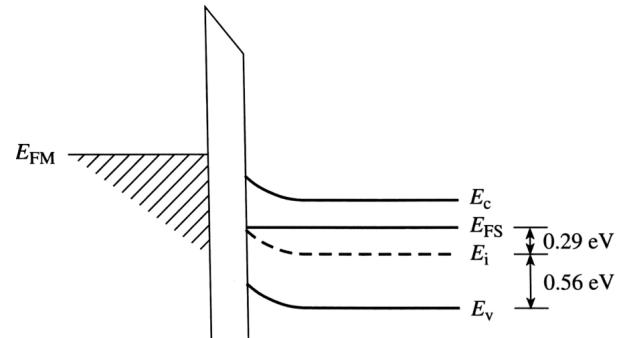


Homework #6

pn Junction large-signal & MOS capacitors – **100 points**
DUE @ Beginning of Class: Thursday, October 19

- 1) E-Book, problem 1.42 (pg. 443), *hint*: voltage drop will be the same for each of the two top diodes in the circuit (**5 points**)
- 2) E-Book, problem 1.49 (pg. 444), assume an ideal diode (**3 points**)
- 3) E-Book, problem 10.7, given $\phi_{ms} = -0.9932$ V (**3 points**)
- 4) E-Book, problem 10.9, see Example 10.2 for useful information (**4 points**)
- 5) E-Book, problem 10.12 (**10 points**)
- 6) E-Book, problem 10.14, requires some trial-and-error and Fig. 10.16 (**8 points**)
- 7) E-Book, problem 10.23, assume no charge in oxide and use Fig. 10.16 (**16 points**)
- 8) E-Book, problem 10.30 (**16 points**)
- 9) E-Book, problem 10.31, be sure to label your band diagrams (E_{Fm} , E_{Fi} , etc) (**15 points**)
- 10) The energy band diagram for an ideal MOS capacitor with $t_{ox} = 0.2 \mu\text{m}$ operated at 300 K is given below. Note that the applied gate voltage causes band bending in the semiconductor such that $E_F = E_{Fi}$ at the Si-SiO₂ interface. Answer the following questions: (**20 points**)
 - a) Sketch the electrostatic potential inside the semiconductor as a function of position.
 - b) Roughly sketch the electric field inside the oxide and semiconductor as a function of position.
 - c) Do equilibrium conditions prevail inside the semiconductor?
 - d) What is the electron concentration at the Si-SiO₂ interface?
 - e) $N_D = ?$
 - f) $\phi_s = ?$
 - g) What is the approximate applied V_G (indicate how you arrived at answer)?



1) E-Book, problem 1.42 (pg. 443), *hint*: voltage drop will be the same for each of the two top diodes in the circuit (5 points)

- 1.42 (a) The reverse-saturation current of each diode in the circuit shown in Figure P1.42 is $I_s = 6 \times 10^{-14} \text{ A}$. Determine the input voltage V_I required to produce an output voltage of $V_O = 0.635 \text{ V}$. (b) Repeat part (a) if the $1 \text{ k}\Omega$ resistor is changed to $R = 500 \Omega$.

a) Since I_s is same for all diodes,

$$V_{D1} = V_{D2}$$

$$I_{D3} = I_s \exp\left(\frac{V_o}{V_t}\right) = (6 \times 10^{-14} \text{ A}) \exp\left(\frac{0.635 \text{ V}}{0.0259 \text{ V}}\right) = 2.67 \text{ mA}$$

$$I_R = \frac{0.635 \text{ V}}{1 \times 10^3 \Omega} = 0.635 \text{ mA}$$

By KCL nodal analysis:

$$I_I = I_R + I_{D3}$$

$$I_I = 2.67 \text{ mA} + 0.635 \text{ mA} = 3.31 \text{ mA}$$

$$\text{from } I_{D1} = I_s \exp\left(\frac{V_{D1}}{V_t}\right) \Rightarrow V_{D1} = V_t \ln\left(\frac{I_{D1}}{I_s}\right)$$

$$V_{D1} = V_{D2} = (0.0259 \text{ V}) \ln\left(\frac{3.31 \times 10^{-3} \text{ A}}{6 \times 10^{-14} \text{ A}}\right) = 0.641 \text{ V}$$

By KVL loop:

$$V_I = V_{D1} + V_{D2} + V_R = 2(0.641 \text{ V}) + 0.635 \text{ V} = 1.92 \text{ V}$$

b) Repeat with $R = 500 \Omega$

By the same approach as above:

$$V_I = 1.93 \text{ V}$$

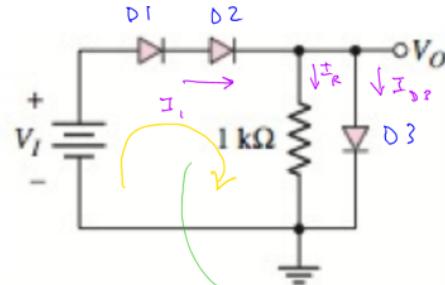


Figure P1.42

$$V_I = V_{D1} + V_{D2} + V_R$$

2) E-Book, problem 1.49 (pg. 444) (3 points)

- 1.49 (a) In the circuit shown in Figure P1.49, find the diode voltage V_D and the supply voltage V such that the current is $I_D = 0.4 \text{ mA}$. Assume the diode cut-in voltage is $V_Y = 0.7 \text{ V}$. (b) Using the results of part (a), determine the power dissipated in the diode.

a) Since the diode is assumed

$$\text{ideal, } V_D \text{ should just be } = V_Y = 0.7 \text{ V}$$

(KVL gives:

$$5 \text{ V} = I_D R + V_D + V$$

$$5 \text{ V} = (0.4 \text{ mA})(4.7 \text{ k}\Omega) + 0.7 \text{ V} + V$$

$$\Rightarrow V = 2.42 \text{ V} \quad , \quad V_D = 0.7 \text{ V}$$

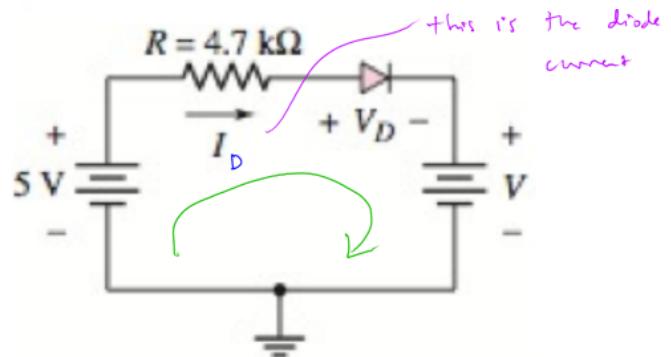
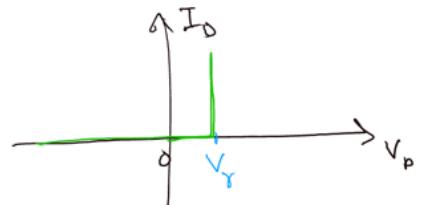


Figure P1.49

Ideal Diode:



b) Dissipated power will be:

$$P = I_D \cdot V_D = (0.4 \text{ mA})(0.7 \text{ V}) = 0.28 \text{ mW}$$

3) E-Book, problem 10.7 (3 points)

- 10.7 (a) Consider the MOS capacitor described in Problem 10.5. For an oxide thickness of $t_{ox} = 20 \text{ nm} = 200 \text{ \AA}$ and an oxide charge of $Q'_{ss} = 5 \times 10^{10} \text{ cm}^{-2}$, calculate the flat-band voltage. (b) Repeat part (a) for an oxide thickness of $t_{ox} = 8 \text{ nm} = 80 \text{ \AA}$.

From 10.5: $N_a = 4 \times 10^{16} \text{ cm}^{-3}$, Al-SiO₂-Si

$$\text{a) } V_{FB} = \phi_{ms} - \frac{Q'_{ss}}{C_{ox}} \quad |$$

$$C_{ox} = \frac{\epsilon_0 \epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm}^2)}{20 \times 10^{-9} \text{ cm}} = 1.726 \times 10^{-7} \text{ F/cm}^2$$

$$V_{FB} = -0.9932 \text{ V} - \frac{5 \times 10^{10} \text{ cm}^{-2}}{1.726 \times 10^{-7} \text{ F/cm}^2} \left(1.6 \times 10^{-19} \text{ C} \right) = -1.04 \text{ V} \quad |$$

units: $\frac{1}{\text{F}} = \frac{\text{V}}{\text{C}} = \text{V}$

b) Using same approach:

$$V_{FB} = -1.012 \text{ V} \quad |$$

4) E-Book, problem 10.9 (4 points)

- 10.9 Consider an aluminum gate-silicon dioxide-p-type silicon MOS structure with $t_{ox} = 450 \text{ \AA}$. The silicon doping is $N_a = 2 \times 10^{16} \text{ cm}^{-3}$ and the flat-band voltage is $V_{FB} = -1.0 \text{ V}$. Determine the fixed oxide charge Q'_{ss} .

$$\phi_{ms} = \phi_m' - \left(\chi' + \frac{E_g}{2e} + \phi_{fp} \right)$$

$$\phi_{fp} = V_t \ln \left(\frac{N_a}{n_i} \right) = (0.025 \text{ aV}) \ln \left(\frac{2 \times 10^{16} \text{ cm}^{-3}}{1.5 \times 10^{10} \text{ cm}^{-3}} \right) = 0.365 \text{ V}$$

$$\phi_{ms} = 3.20 \text{ V} - (3.25 \text{ V} + \frac{1.12 \text{ eV}}{2e} + 0.365 \text{ V}) = -0.975 \text{ V} \quad |$$

for Al-Si, example 10.2 in E-Book

$$V_{FB} = \phi_{ms} - \frac{Q'_{ss}}{C_{ox}} \Rightarrow Q'_{ss} = (\phi_{ms} - V_{FB}) C_{ox} \quad |$$

$$C_{ox} = \frac{\epsilon_0 \epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm}^2)}{45 \times 10^{-9} \text{ cm}} = 7.67 \times 10^{-8} \text{ F/cm}^2 \quad |$$

$$Q'_{ss} = \left[-0.975 \text{ V} - (-1 \text{ V}) \right] (7.67 \times 10^{-8} \text{ F/cm}^2) = 1.92 \times 10^{-9} \text{ C/cm}^2 \quad |$$

OR

$$\frac{Q'_{ss}}{e} = 1.2 \times 10^{10} \text{ cm}^{-2} \quad |$$

double the indicated points

5) E-Book, problem 10.12 (10 points)

- 10.12** A 400-Å oxide is grown on p-type silicon with $N_a = 5 \times 10^{15} \text{ cm}^{-3}$. The flat-band voltage is -0.9 V . Calculate the surface potential at the threshold inversion point as well as the threshold voltage assuming negligible oxide charge. Also find the maximum space charge width for this device.

$$\phi_{fp} = V_t \ln \left(\frac{N_a}{n_i} \right) = (0.0259 \text{ V}) \ln \left(\frac{5 \times 10^{15} \text{ cm}^{-3}}{1.5 \times 10^{10} \text{ cm}^{-3}} \right) = 0.329 \text{ V}$$

surface potential at threshold inversion:

$$\phi_s = 2\phi_{fp} = 0.659 \text{ V}$$

$$V_{FB} = \phi_{ms} - \frac{Q_{ss}'}{C_{ox}} = -0.9 \text{ V}$$

$$V_T = \frac{|Q_{so}^{\prime \text{ (max)}}|}{C_{ox}} + V_{FB} + \phi_s$$

$$\text{and: } |Q_{so}^{\prime \text{ (max)}}| = e N_a x_{dt}$$

$$x_{dt} = \left[\frac{4 \epsilon_s \epsilon_0 \phi_{fp}}{e N_a} \right]^{\frac{1}{2}} = \left[\frac{4(11.7)(8.85 \times 10^{-14} \text{ F/cm})(0.329 \text{ V})}{(1.6 \times 10^{-19} \text{ C})(5 \times 10^{15} \text{ cm}^{-3})} \right]^{\frac{1}{2}} = 0.413 \times 10^{-4} \text{ cm}$$

$$|Q_{so}^{\prime \text{ (max)}}| = (1.6 \times 10^{-19} \text{ C})(5 \times 10^{15} \text{ cm}^{-3})(0.413 \times 10^{-4} \text{ cm}) = 3.304 \times 10^{-8} \text{ C/cm}^2$$

$$\text{and: } C_{ox} = \frac{\epsilon_0 \epsilon_s}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{40 \times 10^{-7} \text{ cm}} = 8.63 \times 10^{-8} \text{ F/cm}^2$$

$$V_T = \frac{3.304 \times 10^{-8} \text{ C/cm}^2}{8.63 \times 10^{-8} \text{ F/cm}^2} - 0.9 \text{ V} + 0.659 \text{ V} = 0.142 \text{ V}$$

double the indicated points

6) E-Book, problem 10.14 (8 points)

- 10.14** Consider a MOS device with the following parameters: p⁺ polysilicon gate, n-type silicon substrate, $t_{ox} = 18 \text{ nm} = 180 \text{ \AA}$, and $Q'_{ss} = 4 \times 10^{10} \text{ cm}^{-2}$. Determine the silicon doping concentration such that the threshold voltage is in the range $-0.35 \leq V_{TP} \leq -0.25 \text{ V}$.

Based on the given info:

$$C_{ox} = \frac{\epsilon_0 \times \epsilon_r}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm}^2)}{18 \times 10^{-7} \text{ cm}} = 1.92 \times 10^{-7} \text{ F/cm}^3$$

unit conversion for Q_{ss} :

$$Q'_{ss} = (1.6 \times 10^{-19} \text{ C})(4 \times 10^{10} \text{ cm}^{-2}) = 6.4 \times 10^{-9} \text{ C/cm}^2$$

For V_{TP} :

$$V_{TP} = -\frac{(Q'_{so}(\text{max}) + Q'_{ss})}{C_{ox}} + \phi_{ms} - 2\phi_{fn}$$

Key eqns with N_d :

$$\phi_{fn} = V_t \ln \left(\frac{N_d}{n_i} \right) = (0.0259 \text{ V}) \ln \left(\frac{N_d}{1.8 \times 10^{10} \text{ cm}^{-3}} \right)$$

dependence

$$|Q'_{so}(\text{max})| = e N_d x_{st} = (1.6 \times 10^{-19} \text{ C}) N_d \left[\frac{4(11.7)(8.85 \times 10^{-14} \text{ F/cm}) \phi_{fn}}{(1.6 \times 10^{-19} \text{ C}) N_d} \right]^{1/2}$$

$$x_{st} = \left[\frac{4 \epsilon_r \epsilon_0 \phi_{fn}}{e N_d} \right]^{1/2}$$

$$\phi_{ms} \approx \text{Fig. 10.16} (N_d)$$

Use trial and error to find N_d

one solution:

$$N_d = 5 \times 10^{16} \text{ cm}^{-3}$$

yields

$V_{TP} = -0.303 \text{ V}$, which is within the given range

NOTE: actual answer for N_d will vary, but the approach to obtaining the answer should be as above.

double the indicated points

7) E-Book, problem 10.23 (16 points)

- 10.23** An ideal MOS capacitor with an n⁺ polysilicon gate has a silicon dioxide thickness of $t_{ox} = 12 \text{ nm} = 120 \text{ \AA}$ on a p-type silicon substrate doped at $N_a = 10^{16} \text{ cm}^{-3}$. Determine the capacitance C_{ox} , C'_{FB} , C'_{min} , and $C'(\text{inv})$ at (a) $f = 1 \text{ Hz}$ and (b) $f = 1 \text{ MHz}$. (c) Determine V_{FB} and V_T . (d) Sketch C'/C_{ox} versus V_G for parts (a) and (b).

a) For low-frequency, $f = 1 \text{ Hz}$

$$C_{ox} = \frac{\epsilon_0 \epsilon_{ox}}{t_{ox}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{12 \times 10^{-7} \text{ cm}} = 2.88 \times 10^{-7} \text{ F/cm}^2$$

$$C'_{FB} = \frac{\epsilon_0 \epsilon_{ox}}{t_{ox} + \left(\frac{\epsilon_{ox}}{\epsilon_s} \right) \sqrt{\frac{V_t \epsilon_s \epsilon_0}{e N_a}}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{12 \times 10^{-7} \text{ cm} + \left(\frac{3.9}{11.7} \right) \sqrt{\frac{(0.025 \text{ uV})(11.7)(8.85 \times 10^{-14} \text{ F/cm})}{(1.6 \times 10^{19} \text{ C})(10^{16} \text{ cm}^{-3})}}} = 1.35 \times 10^{-7} \text{ F/cm}^2$$

$$C'_{min} = \frac{\epsilon_0 \epsilon_{ox}}{t_{ox} + \left(\frac{\epsilon_{ox}}{\epsilon_s} \right) \times x_{dT}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{12 \times 10^{-7} \text{ cm} + \left(\frac{3.9}{11.7} \right) (3.0 \times 10^{-5} \text{ cm})} = 3.08 \times 10^{-8} \text{ F/cm}^2$$

$$\phi_{fp} = V_t \ln \left(\frac{N_a}{n_i} \right) = (0.025 \text{ uV}) \ln \left(\frac{10^{16}}{1.5 \times 10^{10}} \right) = 0.347 \text{ V}$$

$$x_{dT} = \left[\frac{4 \epsilon_0 \phi_{fp}}{e N_a} \right]^{1/2} = \left[\frac{4(11.7)(8.85 \times 10^{-14} \text{ F/cm})(0.347 \text{ V})}{(1.6 \times 10^{19} \text{ C})(10^{16} \text{ cm}^{-3})} \right]^{1/2} = 3.0 \times 10^{-5} \text{ cm}$$

$$C'(\text{inv}) = C_{ox} = 2.88 \times 10^{-7} \text{ F/cm}^2$$

b) $f = 1 \text{ MHz}$

⇒ everything unchanged except $C'(\text{inv})$ which now = C'_{min} :

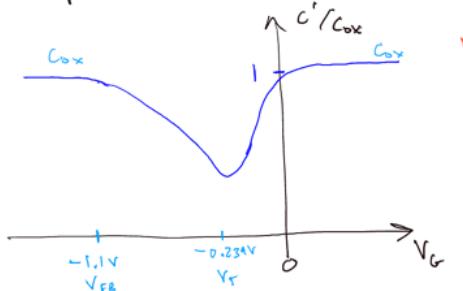
$$C_{ox} = 2.88 \times 10^{-7} \text{ F/cm}^2 \quad C'_{min} = 3.08 \times 10^{-8} \text{ F/cm}^2$$

$$C'_{FB} = 1.35 \times 10^{-7} \text{ F/cm}^2 \quad C'(\text{inv}) = C'_{min} = 3.08 \times 10^{-8} \text{ F/cm}^2$$

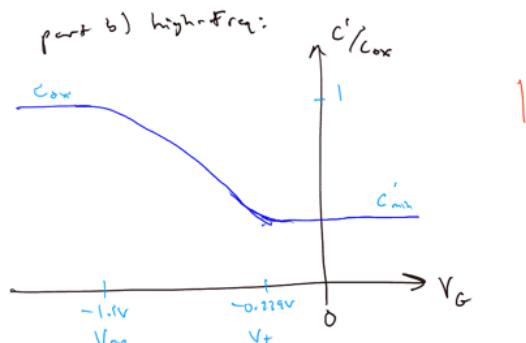
c) $V_{FB} = \phi_{ms} \approx -1.10 \text{ V}$ (from Fig. 10-16)

$$V_{TN} = \frac{1(Q_{so}(\text{max}))}{C_{ox}} + V_{FB} + 2\phi_{fp} = \frac{(1.6 \times 10^{-19} \text{ C})(10^{16} \text{ cm}^{-3})(3.08 \times 10^{-5} \text{ cm})}{2.88 \times 10^{-7} \text{ F/cm}^2} - 1.10 \text{ V} + 2(0.347 \text{ V}) = -0.239 \text{ V}$$

d) For part a) low-freq:



part b) high-freq:



double the indicated points

8) E-Book, problem 10.30 (16 points)

- 10.30** The high-frequency $C-V$ characteristic curve of a MOS capacitor is shown in Figure P10.30. The area of the device is $2 \times 10^{-3} \text{ cm}^2$. The metal-semiconductor work function difference is $\phi_{ms} = -0.50 \text{ V}$, the oxide is SiO_2 , the semiconductor is silicon, and the semiconductor doping concentration is $2 \times 10^{16} \text{ cm}^{-3}$. (a) Is the semiconductor n or p type? (b) What is the oxide thickness? (c) What is the equivalent trapped oxide charge density? (d) Determine the flat-band capacitance.

a) Semiconductor is **n-type** because |
accumulation region occurs at more positive V_G

$$b) C_{ox}^i = \frac{\epsilon_{ox} \epsilon_0}{t_{ox}} = \frac{C_{ox}}{A} = \frac{200 \times 10^{-12} \text{ F}}{2 \times 10^{-3} \text{ cm}^2} = 10^{-7} \text{ F/cm}^2 |$$

$$\downarrow \\ t_{ox} = \frac{\epsilon_{ox} \epsilon_0}{10^{-7} \text{ F/cm}^2} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{10^{-7} \text{ F/cm}^2} = 3.45 \times 10^{-6} \text{ cm} = 34.5 \text{ nm } 2$$

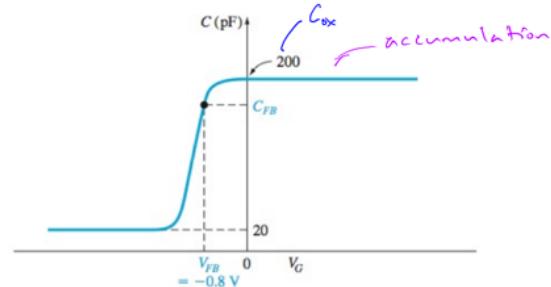


Figure P10.30 | Figure for Problem 10.30.

$$c) V_{FB} = \phi_{ms} - \frac{Q_{ss}^i}{C_{ox}} \Rightarrow -0.8 \text{ V} = -0.50 \text{ V} - \frac{Q_{ss}^i}{10^{-7} \text{ F/cm}^2} \\ \therefore Q_{ss}^i = 3 \times 10^{-8} \text{ C/cm}^2 \text{ OR } 1.88 \times 10^{-11} \text{ cm}^{-2} 2 \\ \text{either is acceptable}$$

$$d) C_{FB}^i = \frac{\epsilon_{ox} \epsilon_0}{t_{ox} + \left(\frac{\epsilon_{ox}}{\epsilon_s} \right) \sqrt{V_t \left(\frac{\epsilon_s \epsilon_0}{e N_d} \right)}} = \frac{(3.9)(8.85 \times 10^{-14} \text{ F/cm})}{3.45 \times 10^{-6} \text{ cm} + \left(\frac{3.9}{11.7} \right) \sqrt{(0.0259 \text{ V}) \left(\frac{(11.7)(8.85 \times 10^{-14} \text{ F/cm})}{(1.6 \times 10^{16} \text{ C})(2 \times 10^{16} \text{ cm}^{-3})} \right)}} \\ = 7.82 \times 10^{-8} \text{ F/cm}^2 \text{ OR } 156 \text{ pF } 2 \\ \text{either is acceptable}$$

9) E-Book, problem 10.31 (15 points)

- 10.31** Consider the high-frequency $C-V$ plot shown in Figure P10.31. (a) Indicate which points correspond to flat-band, inversion, accumulation, threshold, and depletion modes. (b) Sketch the energy-band diagram in the semiconductor for each condition.

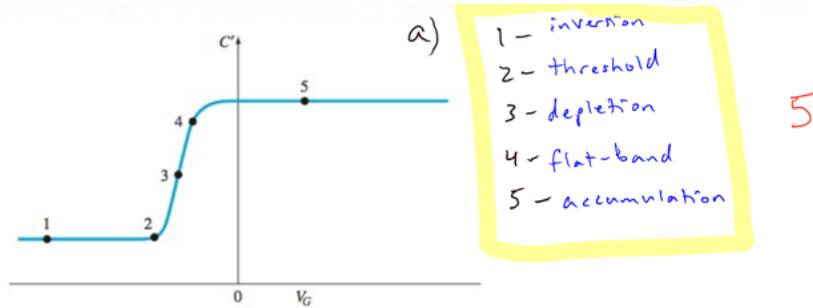
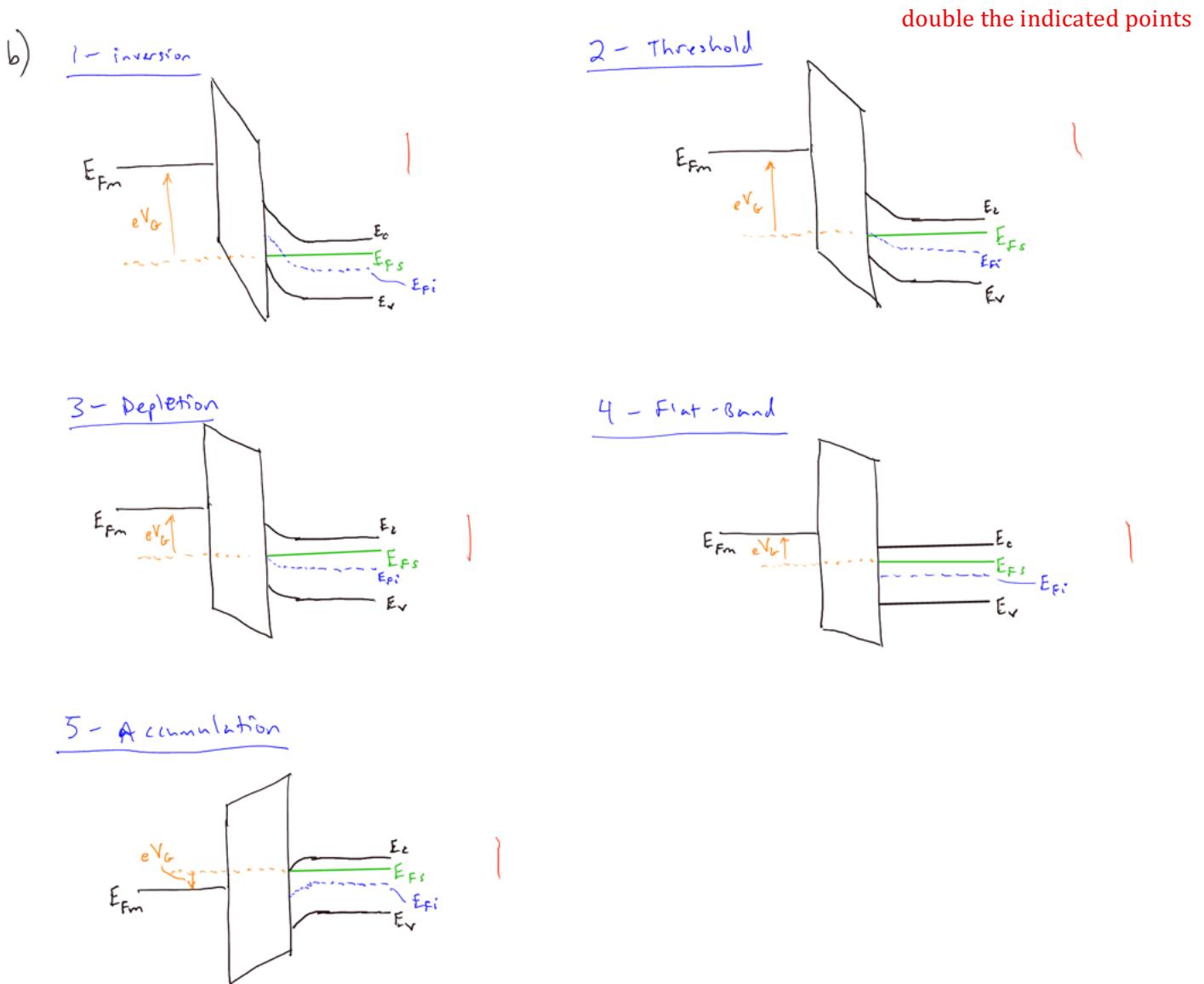


Figure P10.31 | Figure for Problem 10.31.

* n-type semiconductor based on accumulation being at more positive V_G



double the indicated points

10) The energy band diagram for an ideal MOS capacitor with $t_{ox} = 0.2 \mu\text{m}$ operated at 300 K is given below. Note that the applied gate voltage causes band bending in the semiconductor such that $E_F = E_{Fi}$ at the Si-SiO₂ interface. Answer the following questions: (20 points)

a) Sketch the electrostatic potential inside the semiconductor as a function of position.

b) Roughly sketch the electric field inside the oxide and semiconductor as a function of position.

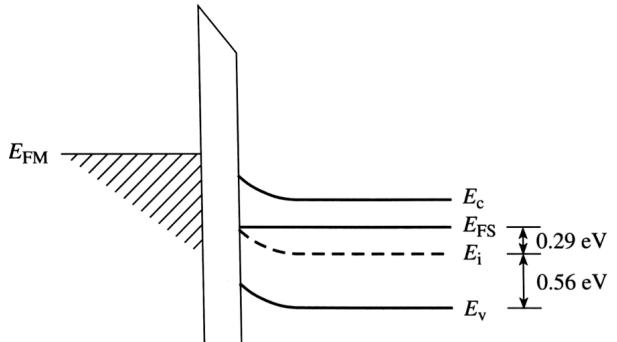
c) Do equilibrium conditions prevail inside the semiconductor?

d) What is the electron concentration at the Si-SiO₂ interface?

e) $N_D = ?$

f) $\phi_s = ?$

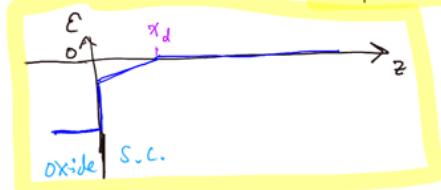
g) What is the approximate applied V_G (indicate how you arrived at answer)?



a) Potential will be the inverse of the bands:



b) E-field is $\propto \frac{dE_c}{dz}$:



c) Yes, E_F is constant / flat in S-C.

d) Since $E_F = E_{Fi}$ at the Si-SiO₂ interface: $n = n_i \exp\left(\frac{E_F - E_{Fi}}{kT}\right) = n_i = 1.5 \times 10^{10} \text{ cm}^{-3}$

e) $N_d = n_{bulk} = n_i \exp\left(\frac{E_{Fs} - E_{Fi}}{kT}\right) = (1.5 \times 10^{10} \text{ cm}^{-3}) \exp\left(\frac{0.29 \text{ eV}}{0.0259 \text{ eV}}\right) = 1.09 \times 10^{15} \text{ cm}^{-3}$

f) $\phi_s = \frac{1}{e} [E_{Fi}|_{bulk} - E_{Fi}|_{surface}] = -0.29 \text{ V}$

g) We know that at $V_G = 0$, $E_{Fm} = E_{Fs}$. Hence the amount of applied V_G can be approximated by the difference between E_{Fm} and E_{Fs} , as shown in the band diagram above, in purple.

$$\therefore V_G \approx -0.8 \text{ V}$$

Answers will vary but should be negative and close to this (within 0.2V) with an explanation